

ADVANCED ELECTRONIC MATERIALS

THIN ELASTOMER FILMS

In article number 1500476, F. M. Weiss et al. describe the preparation of submicrometer-thin polydimethylsiloxane films with a subnanometer root-mean-square surface roughness using alternating current electrospinning. This frontispiece shows an optical micrograph of the electrospayed silicone after UV light curing. The film formation and the flattening during UV-light treatment are in situ observed by means of spectroscopic ellipsometry.

